

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of	:	Attorney Docket No. 2006_0772A
Mitsuhiro OKUNE et al.	:	<b>Confirmation No. 1821</b>
Serial No. 10/581,256	:	Group Art Unit 1792
Filed May 31, 2006	:	Examiner Mahmoud Dahimene
PLASMA ETCHING METHOD	:	<b>Mail Stop: AF</b>

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**RESPONSE AFTER FINAL**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Responsive to the final Office Action dated November 24, 2009, the Applicants herein request consideration of the following remarks.